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**Visible light-induced photocatalytic properties of WO<sub>3</sub> films deposited by dc reactive magnetron sputtering**

Masahiro Imai, Maiko Kikuchi, Nobuto Oka and Yuzo Shigesato

J. Vac. Sci. Technol. A **30**, 031503 (2012); <http://dx.doi.org/10.1116/1.3696876>[+ VIEW DESCRIPTION](#)

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**Influence of chemical composition and deposition conditions on microstructure evolution during annealing of arc evaporated ZrAlN thin films**

L. Rogström, M. P. Johansson, N. Ghafoor, L. Hultman and M. Odén

J. Vac. Sci. Technol. A **30**, 031504 (2012); <http://dx.doi.org/10.1116/1.3698592>[+ VIEW DESCRIPTION](#)

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**Equivalent-circuit model for vacuum ultraviolet irradiation of dielectric films**

Harsh Sinha and J. Leon Shoheit

J. Vac. Sci. Technol. A **30**, 031505 (2012); <http://dx.doi.org/10.1116/1.3693602>[+ VIEW DESCRIPTION](#)

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**Influence of process parameters on properties of reactively sputtered tungsten nitride thin films**

Maria L. Addonizio, Anna Castaldo, Alessandro Antonaia, Emilia Gambale and Laura lemno

J. Vac. Sci. Technol. A **30**, 031506 (2012); <http://dx.doi.org/10.1116/1.3698399>[+ VIEW DESCRIPTION](#)

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**Influence of ionization degree on film properties when using high power impulse magnetron sputtering**

Mattias Samuelsson, Daniel Lundin, Kostas Sarakinos, Fredrik Björefors, Bengt Wälivaara, Henrik Ljungcrantz and U. Helmersson

J. Vac. Sci. Technol. A **30**, 031507 (2012); <http://dx.doi.org/10.1116/1.3700227>[+ VIEW DESCRIPTION](#)

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**Incompatibility of standard III–V compound semiconductor processing techniques with terbium-doped InGaAs of high terbium concentration**

Ashok T. Ramu, Laura E. Clinger, Pernell B. Dongmo, Jeffrey T. Imamura, Joshua M. O. Zide and John E. Bowers

J. Vac. Sci. Technol. A **30**, 031508 (2012); <http://dx.doi.org/10.1116/1.3701951>[+ VIEW DESCRIPTION](#)

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**Thin layer composition profiling with angular resolved x-ray photoemission spectroscopy: Factors affecting quantitative results**T. Conard, W. Vandervorst, [A. Bergmaier](#) and K. KimuraJ. Vac. Sci. Technol. A **30**, 031509 (2012); <http://dx.doi.org/10.1116/1.4704603>[+ VIEW DESCRIPTION](#)

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